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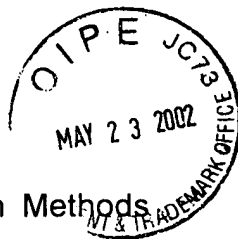
Title: Low Selectivity Deposition Methods

Assignee: Micron Technology, Inc.

Serial No.: 09/643,004

Filing Date: August 21, 2000

Docket No. MI22-1358



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**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**  
**PURSUANT TO 37 C.F.R. §§1.56, 1.97 AND 1.98**

In compliance with 37 C.F.R. §§1.56, 1.97 and 1.98, your attention is directed to the United States patent application listed on the attached Form PTO-1449, a copy of which is attached. No admission is made regarding whether the submitted reference is prior art.

This Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this information disclosure statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of this reference is respectfully requested.

Respectfully submitted,

Dated: 23 May 2002

Attorney: James E. Lake  
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